

PAUL SCHERRER INSTITUT

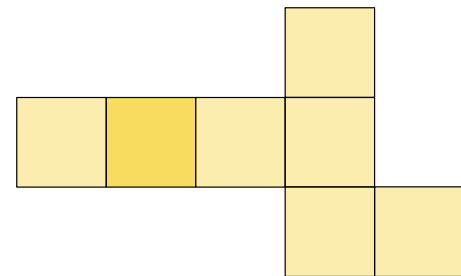
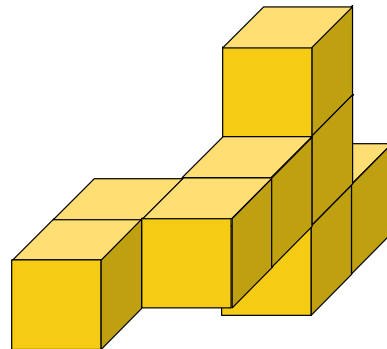
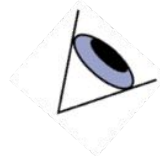
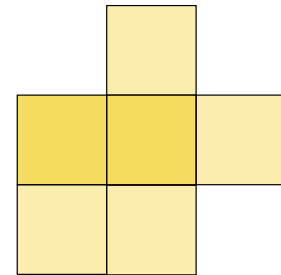
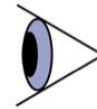
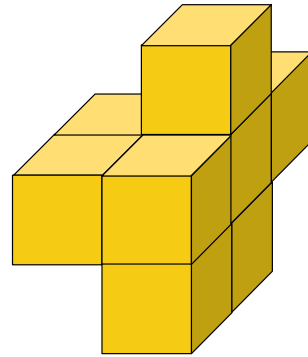
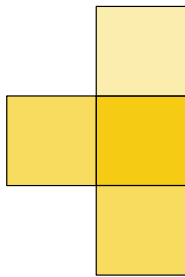
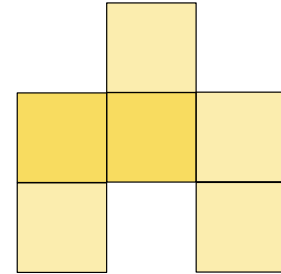
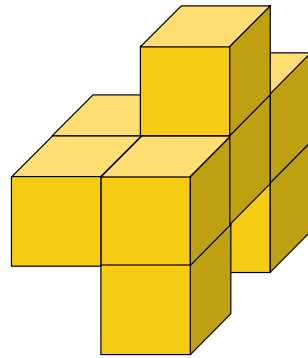


WIR SCHAFFEN WISSEN – HEUTE FÜR MORGEN

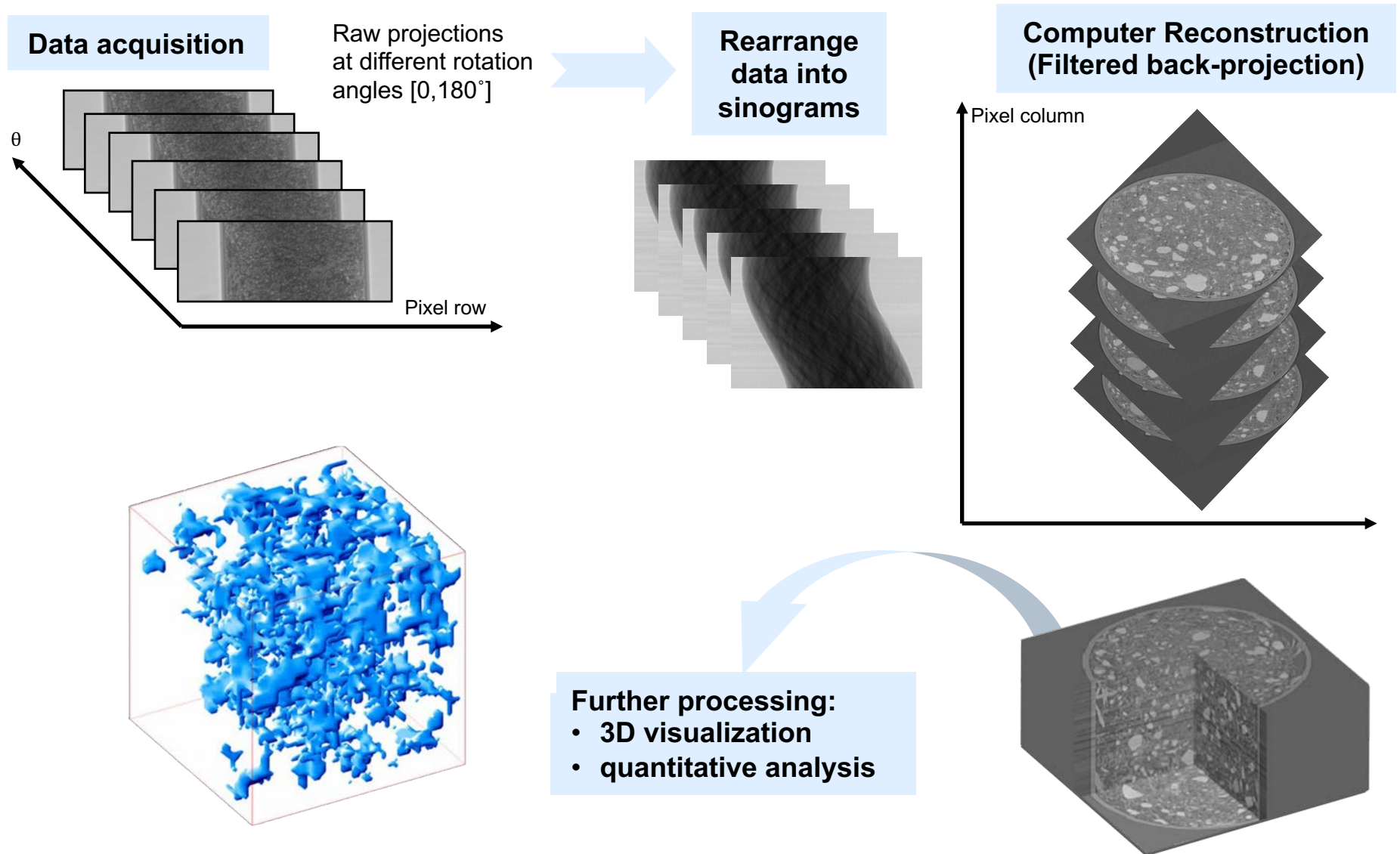
Rasmus Ischebeck

Imaging with Synchrotron Radiation: Tomography and Ptychography

Joint Universities Accelerator School



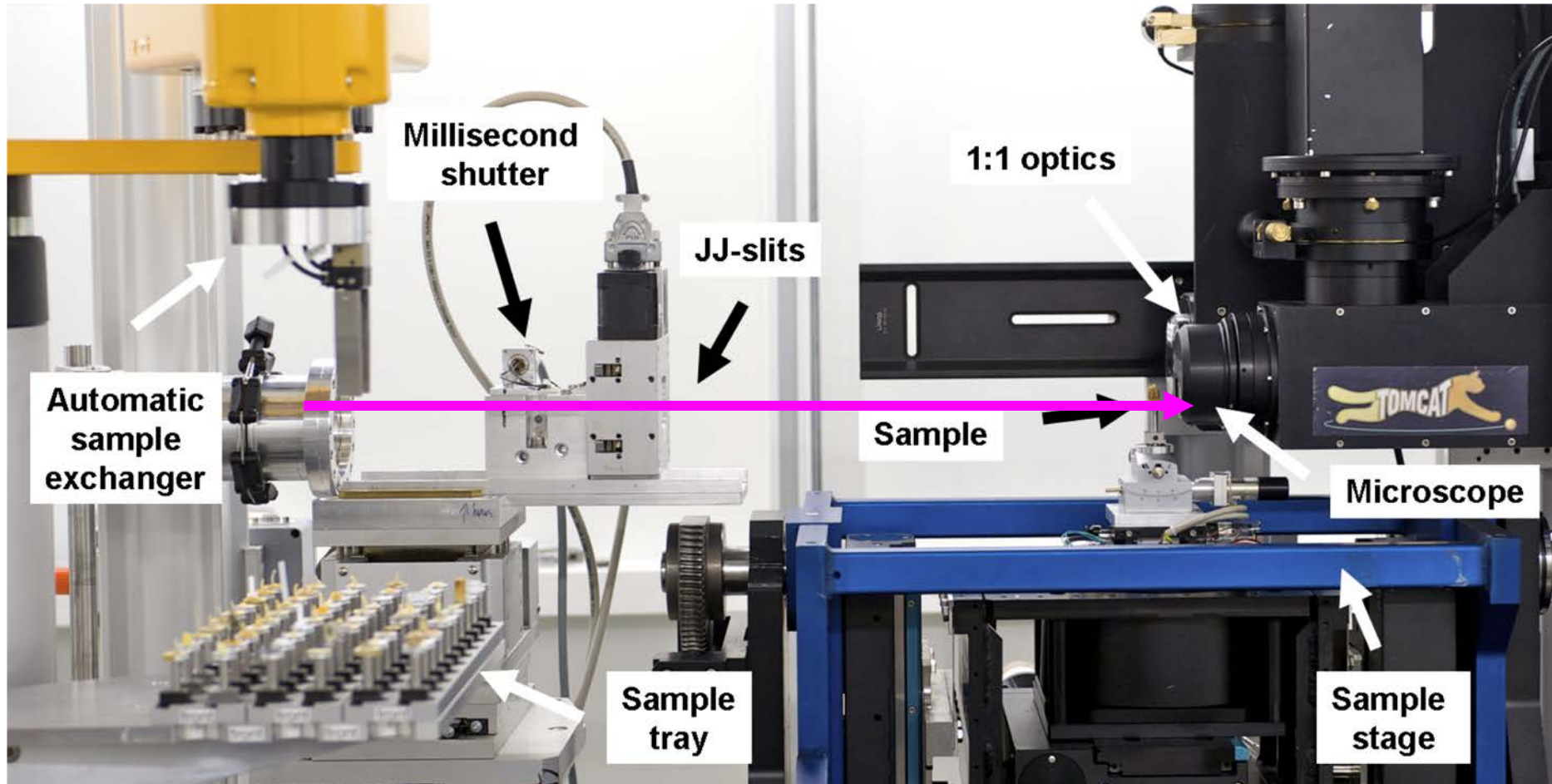
Microtomography principle



State-of-the-art SRXTM (1-50 μm)

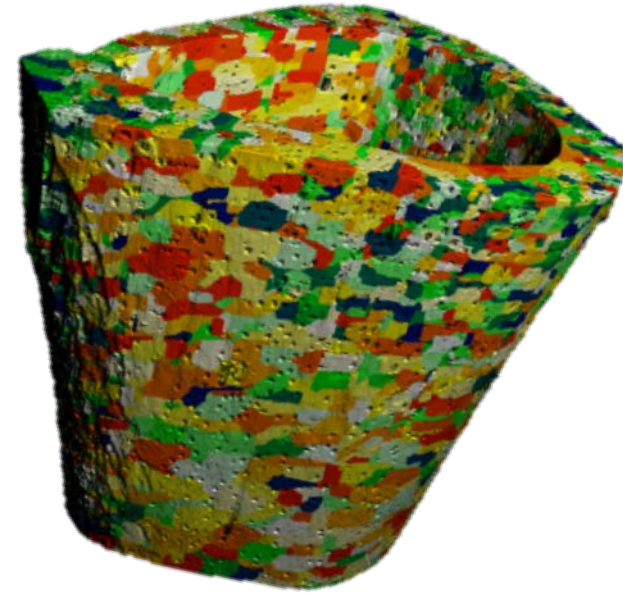
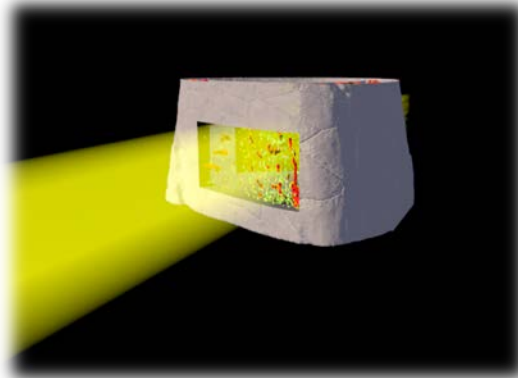
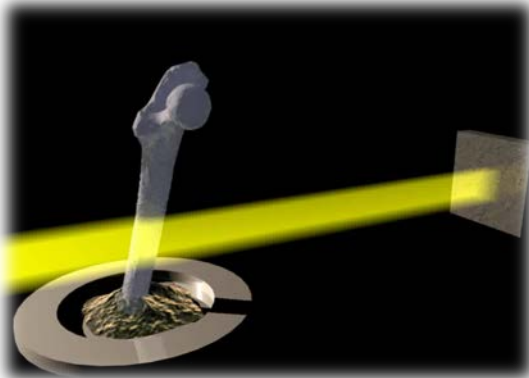


State-of-the-art SRXTM (1-50 μm)

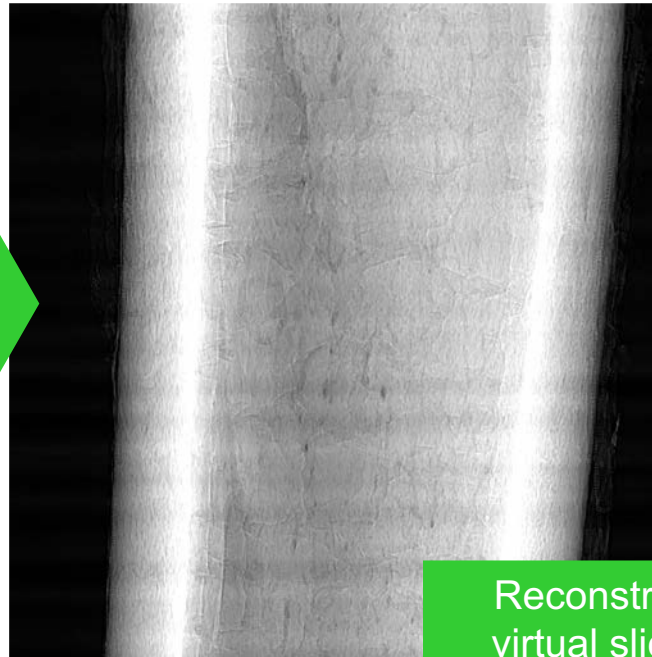


1 micron resolution routinely achieved at 10% MTF

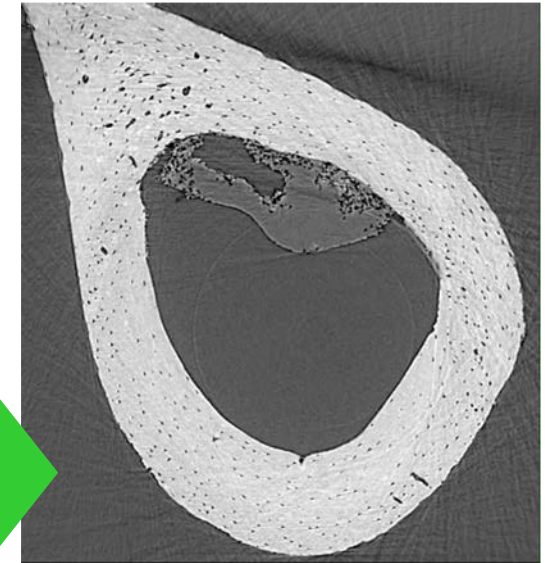
Gathering complex information



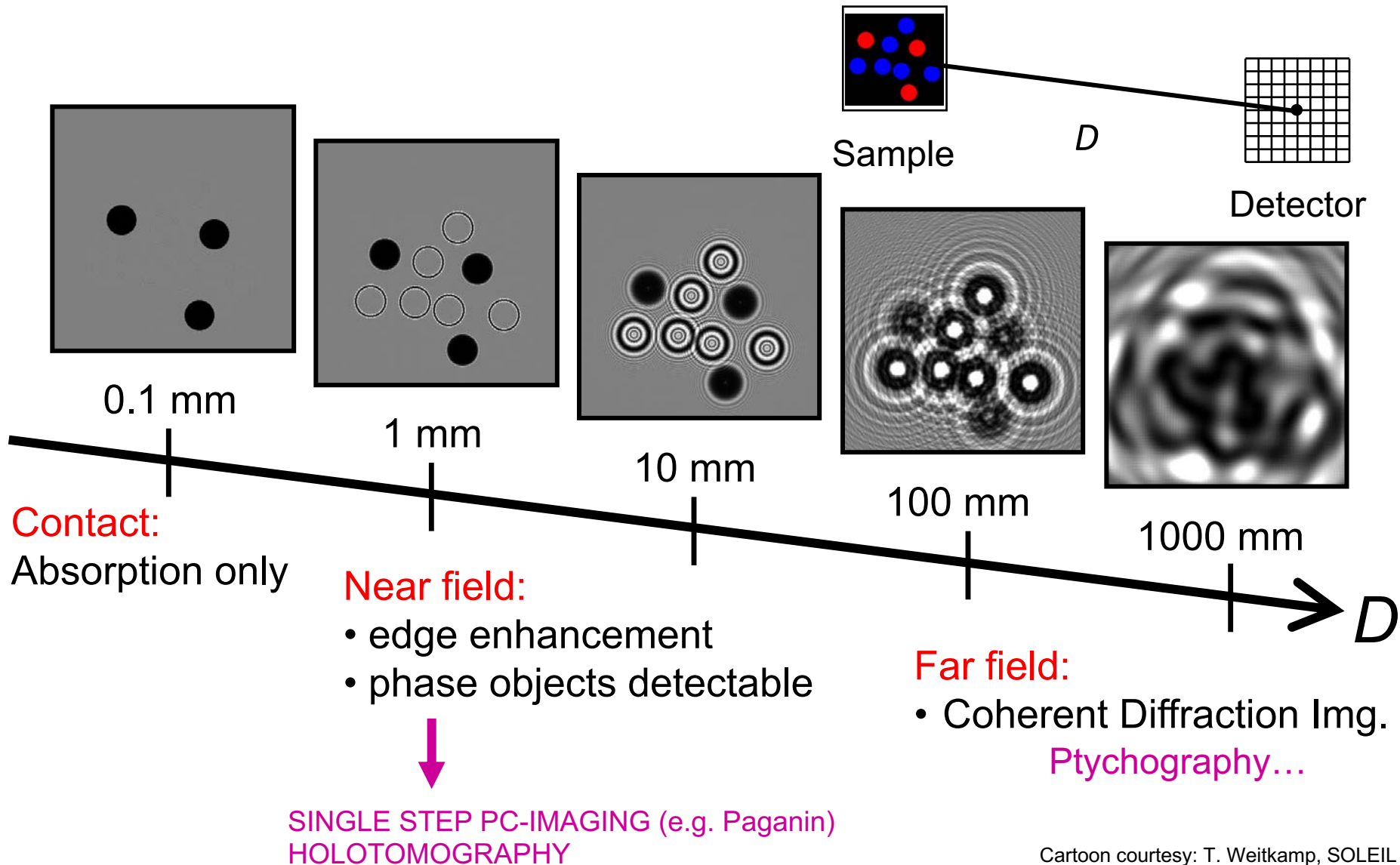
Measure
X-ray projections



Reconstruct
virtual slices



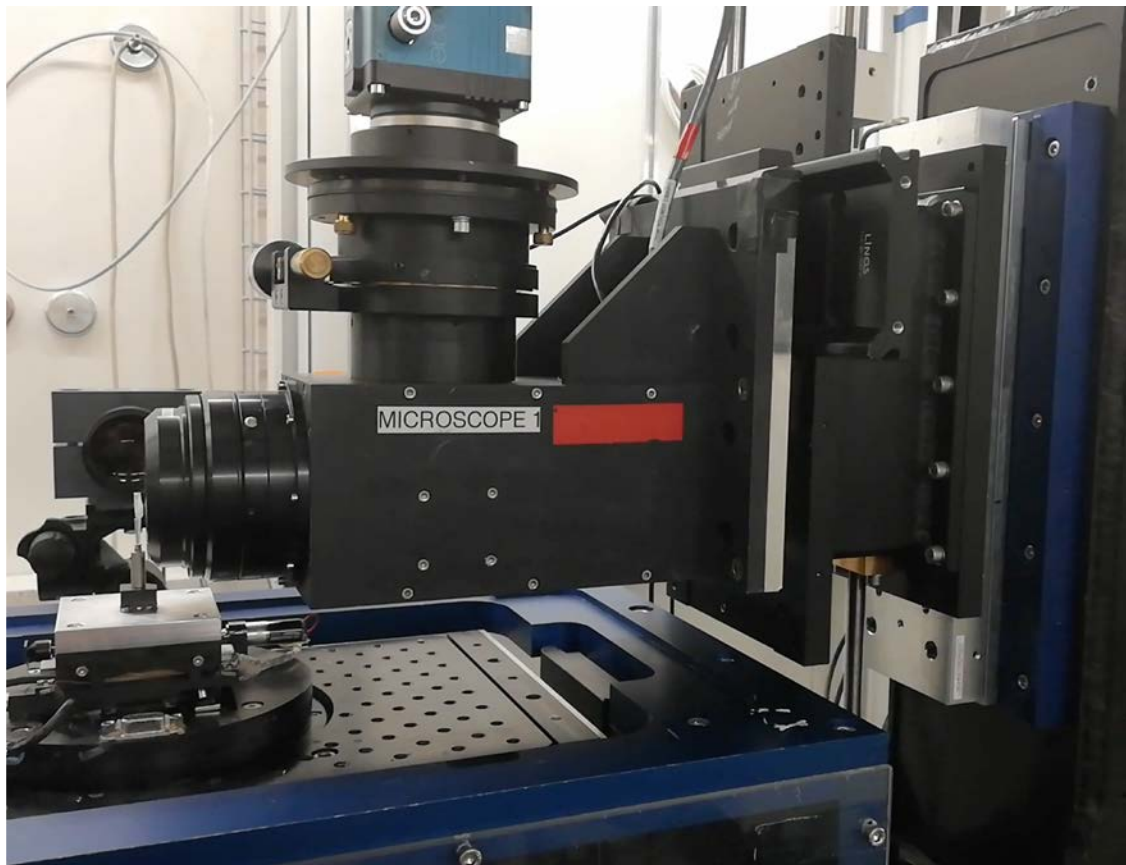
Propagation-based image formation



Cartoon courtesy: T. Weitkamp, SOLEIL

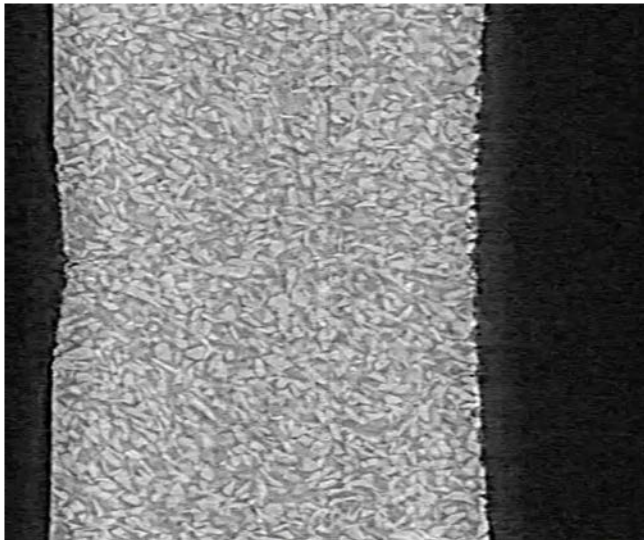
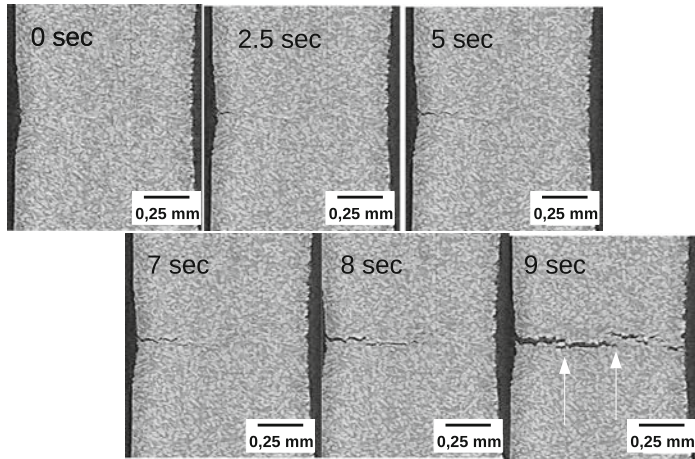
The effect of propagation distance

- Continuous data acquisition during camera motion
- Flat field corrected, shaking reduced



Sample courtesy of E. Cörek, J. Huwiler, University of Basel

In-situ 20 Hz tomographic imaging



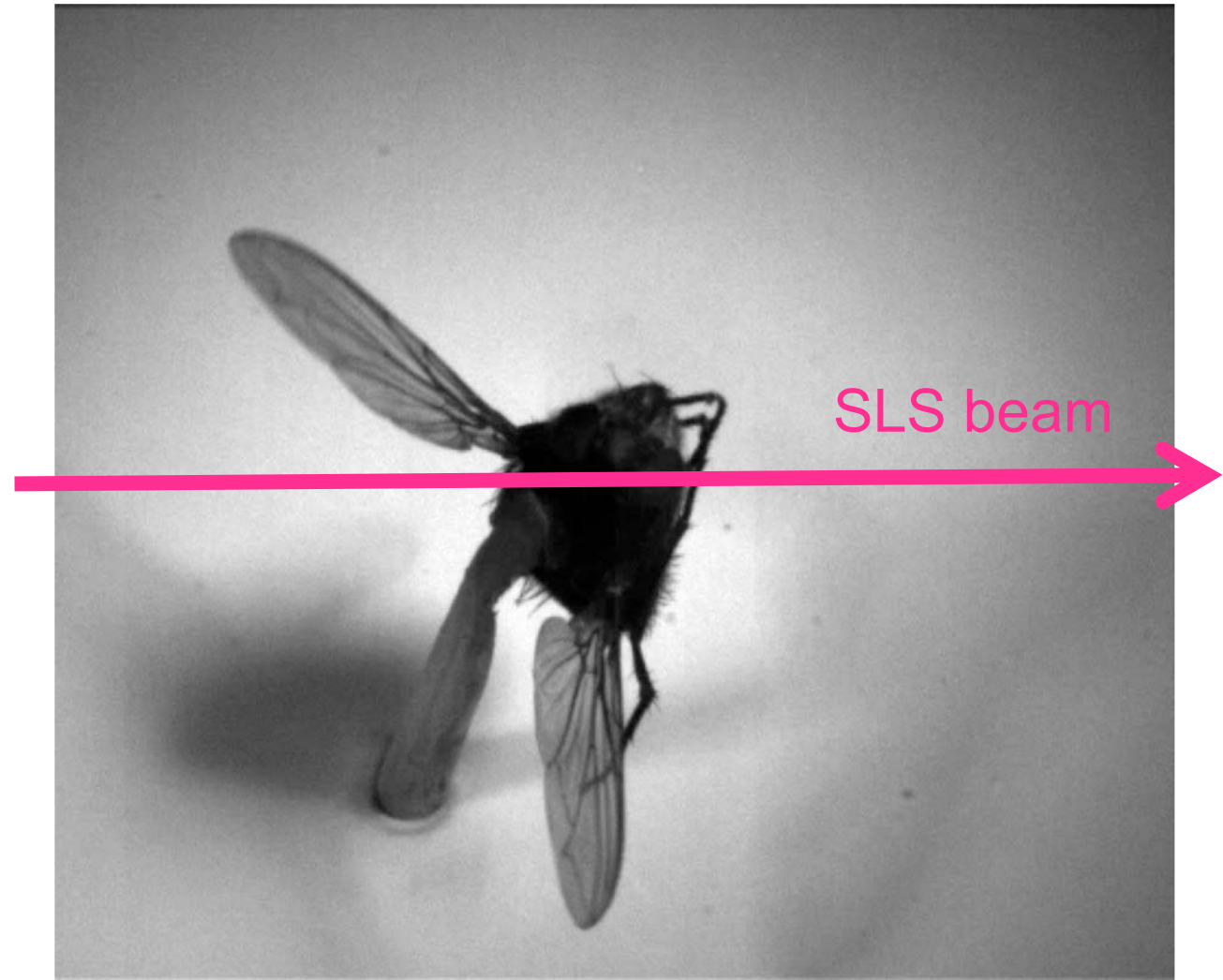
- Crack propagation dynamics under tensile load
- 20 (!) 3D volumes per second

Movie playing in real time (9 seconds, 180 frames)

Maire et. al., Int J Fract (2016)

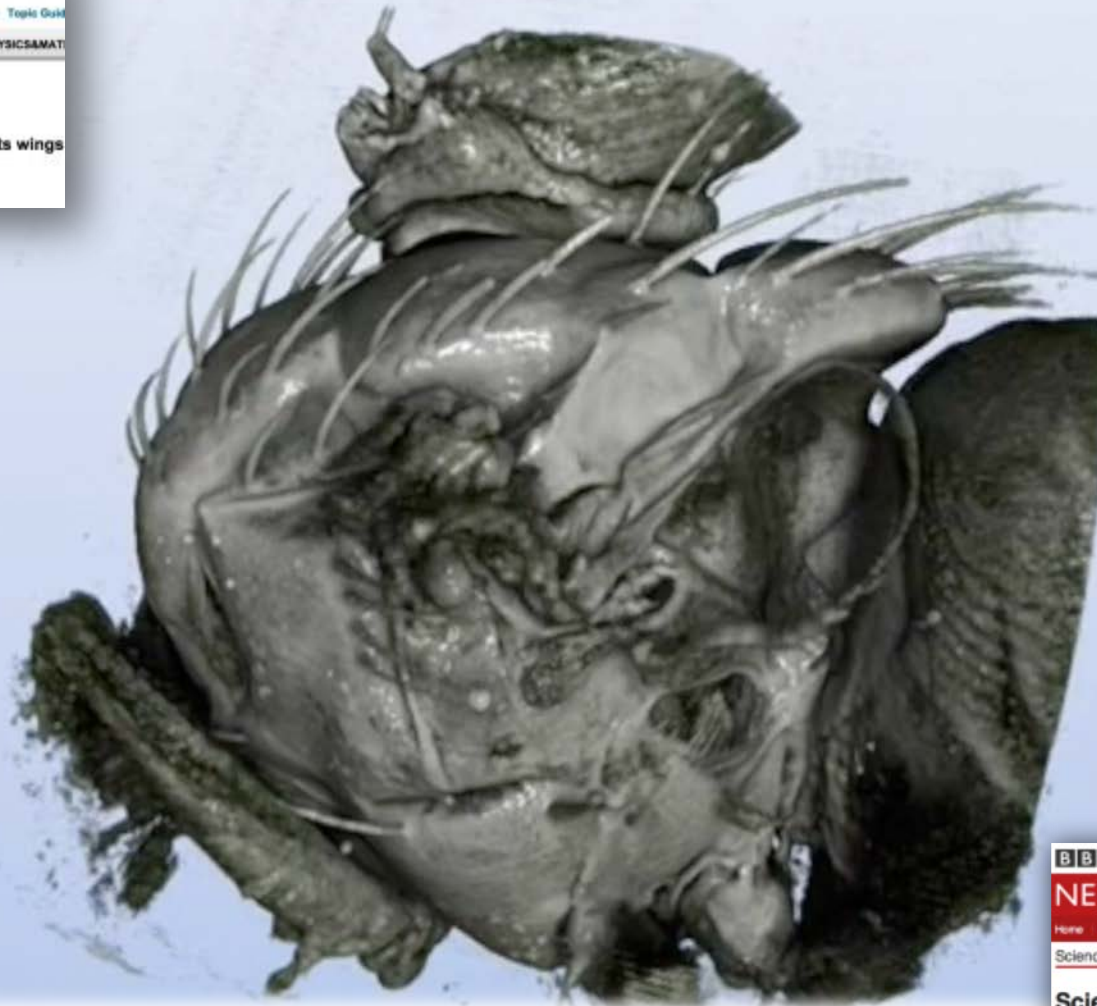
How does a fly really fly?

Wings beat at 150 Hz !!



2500 X-ray images per second...

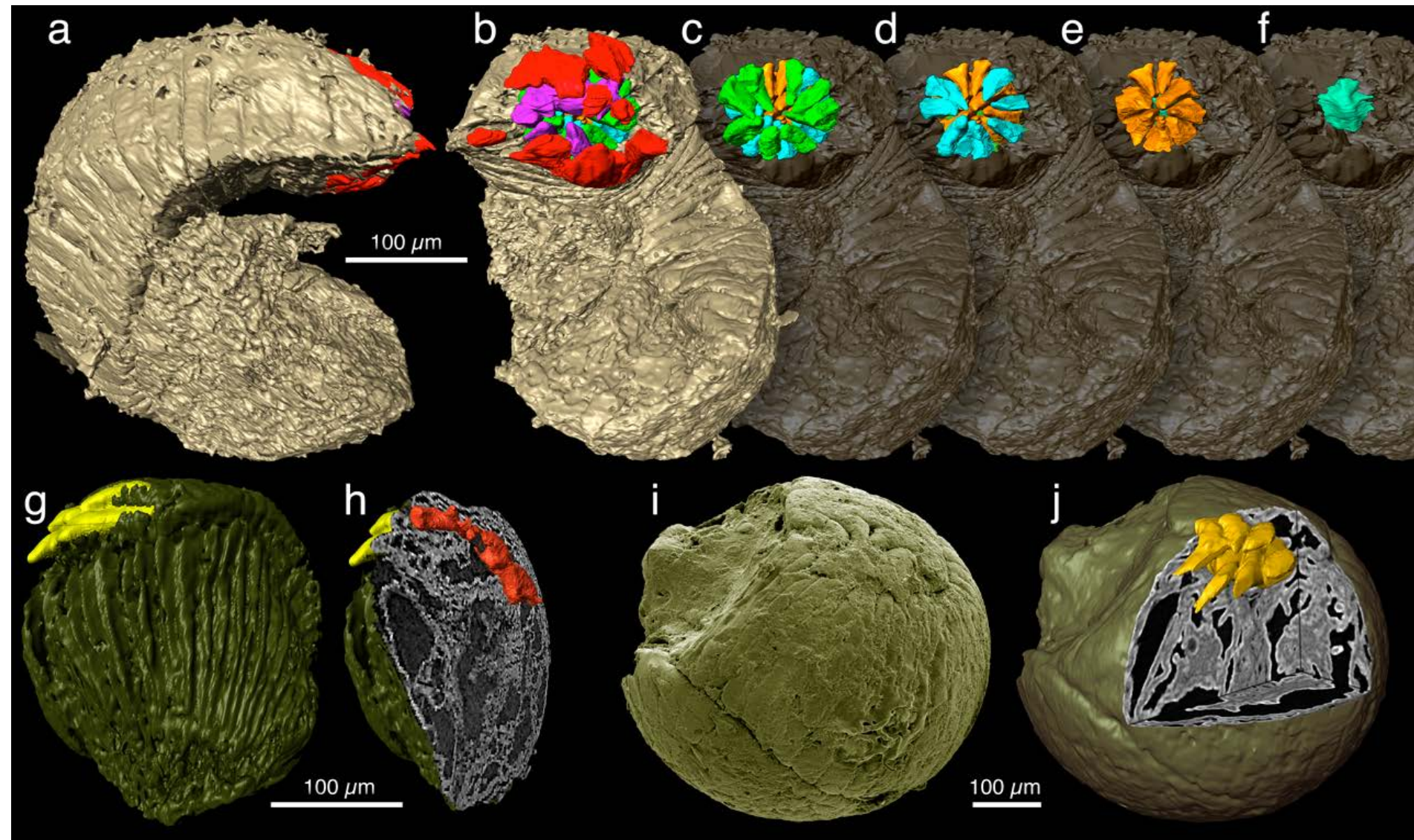
Muscles and tracheal network *during* flight



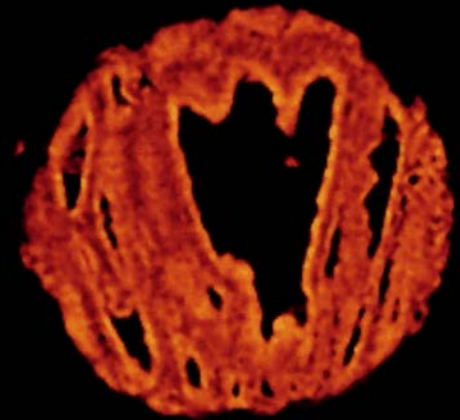
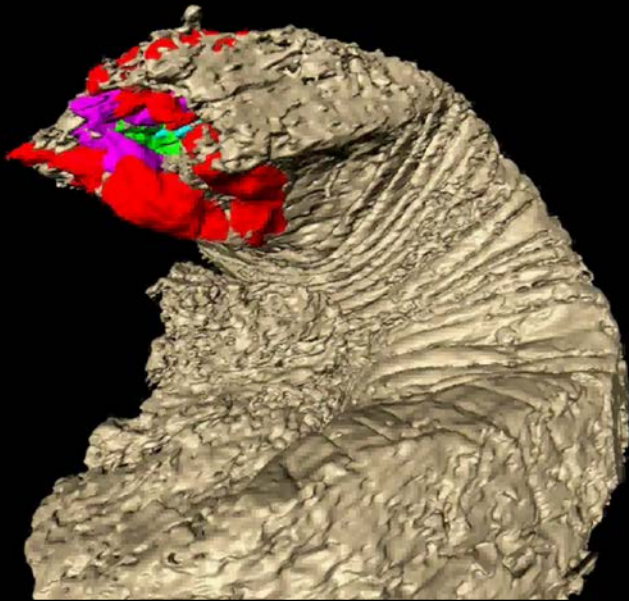
Walker et al., *PLoS Biology* (2014); Mokso et al., *Sci Rep* (2015)



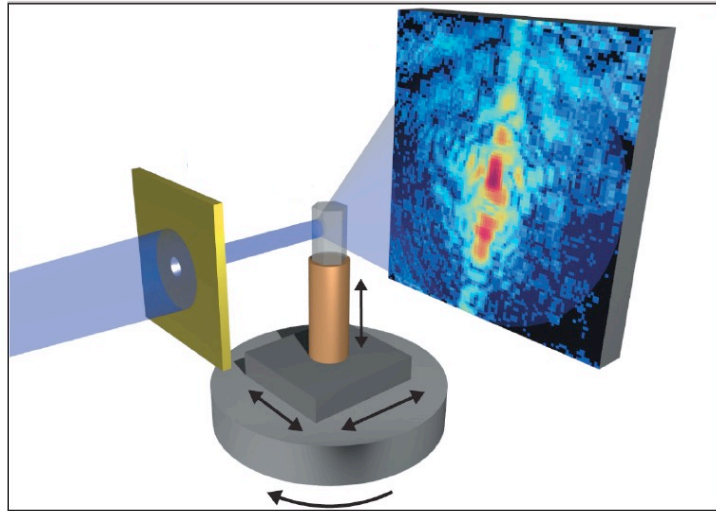
Complex image analysis and data interpretation



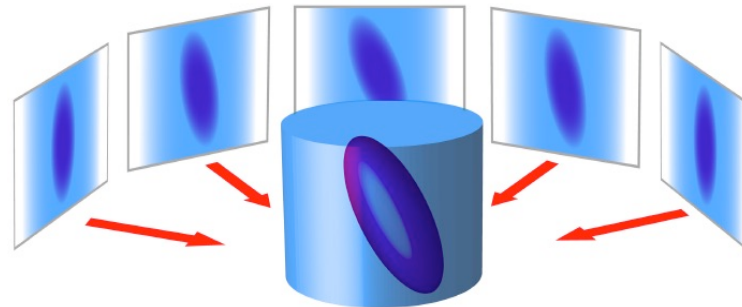
Markuelia, the first “predator” on earth



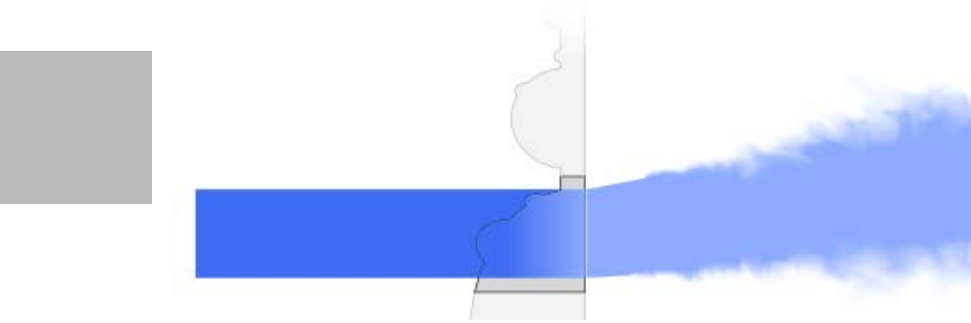
Ptychographic X-ray tomography



Access 3D information via
computed tomography.
→ obtain many projections of the sample
at different angle of incidence.

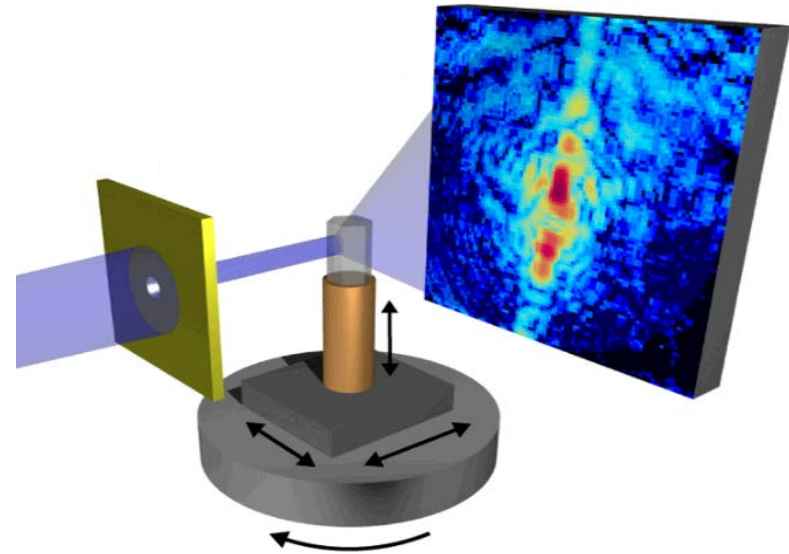


Multi keV X-ray ptychography



- + Lens-less → high resolution
- + multi-keV X-rays → thick samples
→ 3D is important
- + Phase and absorption contrast
- + Quantitative

- Data analysis is involved
- Resolution depends on sample positioning accuracy → involved instrumentation



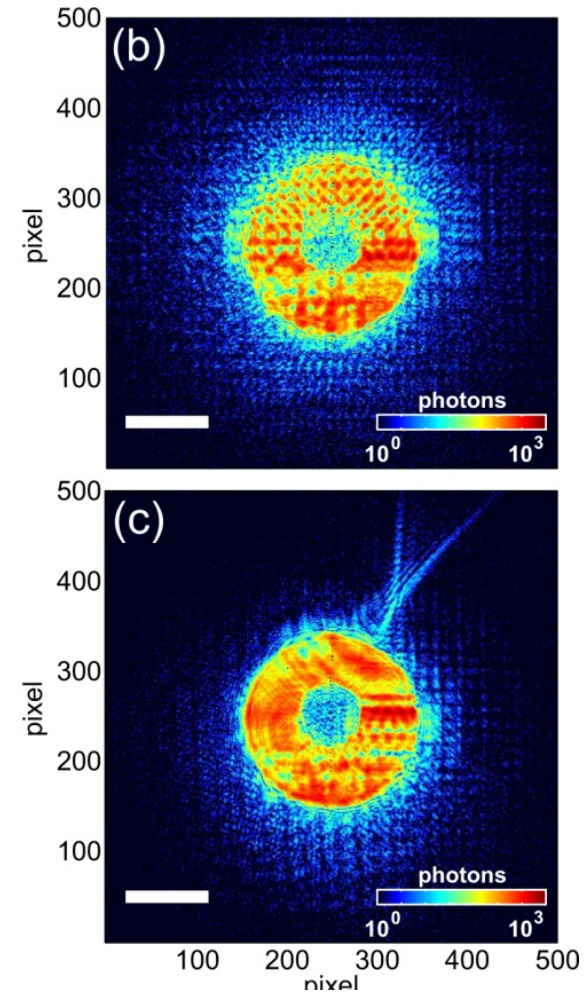
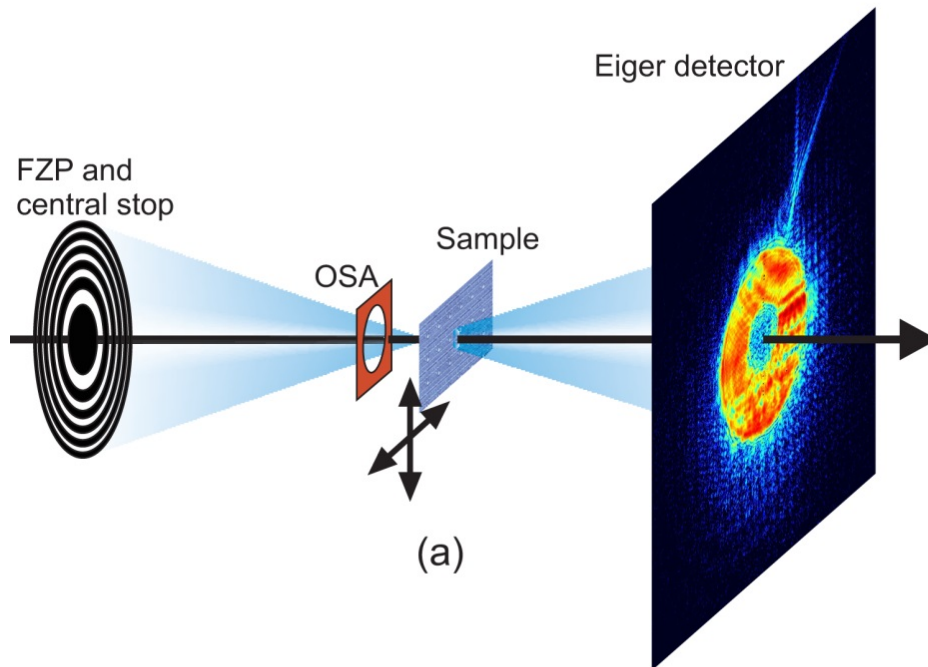
Chip imaging in 2D – The Eiger self portrait

Sample 5 mm downstream of focus

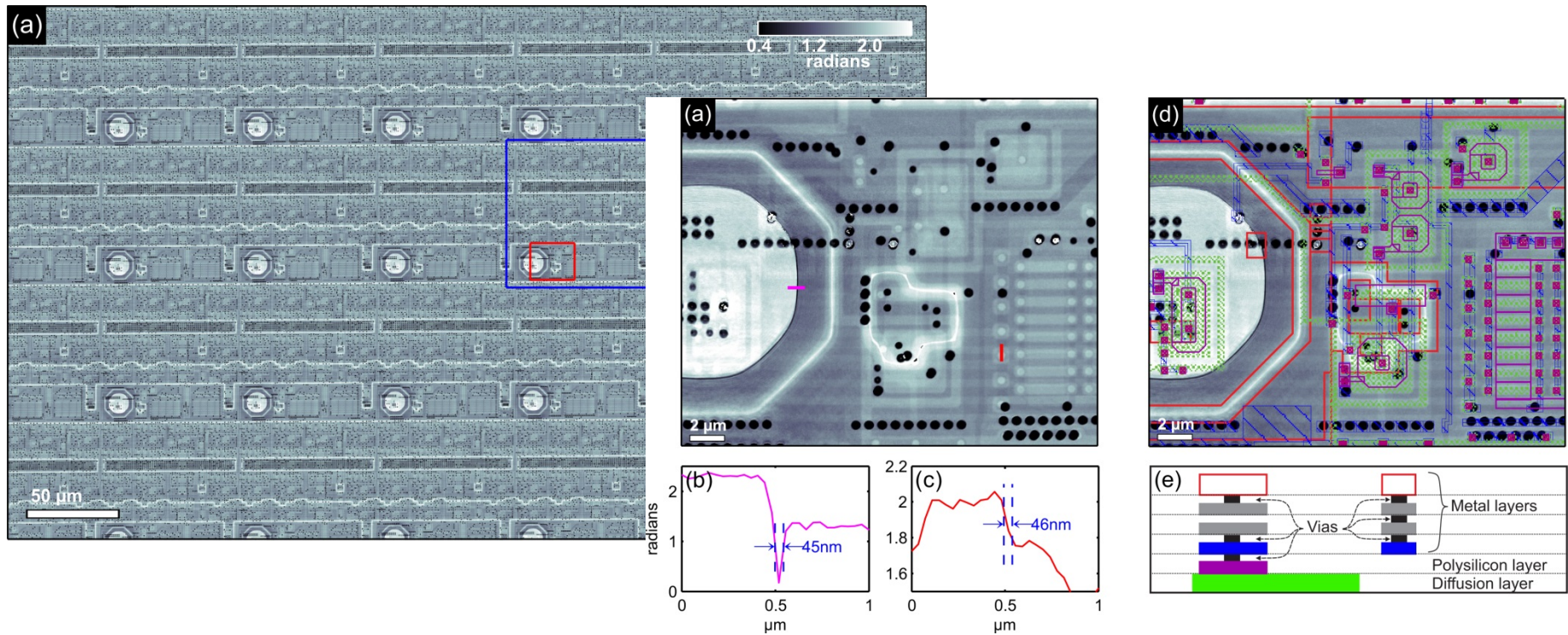
Beam at sample ~ 10 microns

Scanning average step 3.5 microns

Eiger ASIC as sample and Eiger as detector



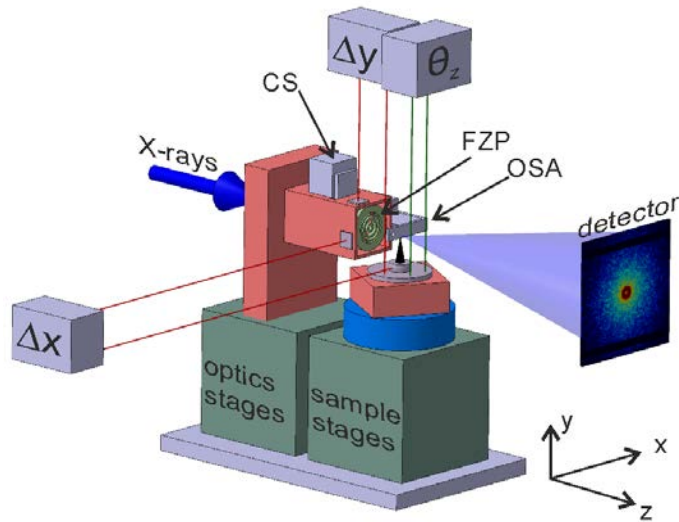
98.4 Mpixel (13,028 x 7,556)
 Resolution 41 nm, 38.4 nm pixel



Two instruments with different sample environments

fIOMNI (flexible tOMography Nano Imaging)

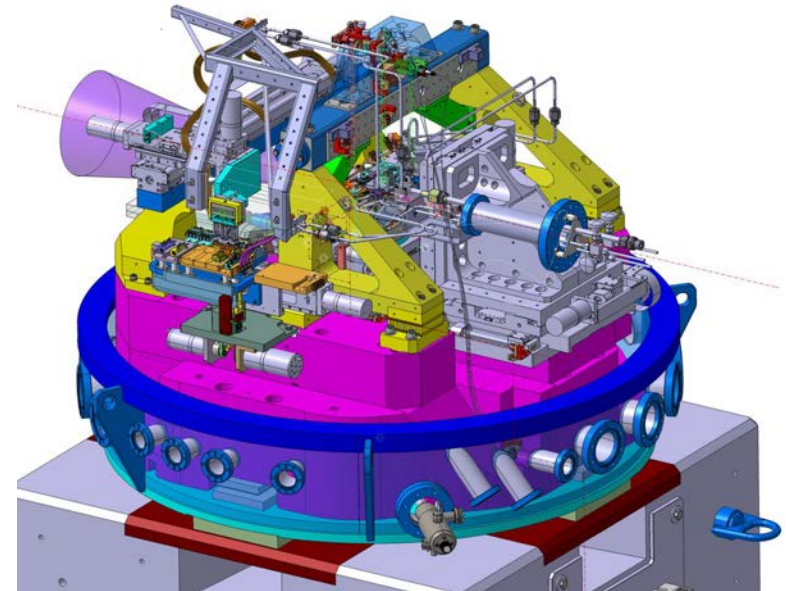
- + nano-positioning, tomography with interferometer
- + room-temperature
- + atmospheric pressure
- + test bench



M. Holler, et al., Rev. Sci. Instrum. 83, 073703 (2012)
 M. Holler and J. Raabe, Opt. Eng. 54(5) 054101 (2015)
 Pat. publication no. WO 2012079875 A1

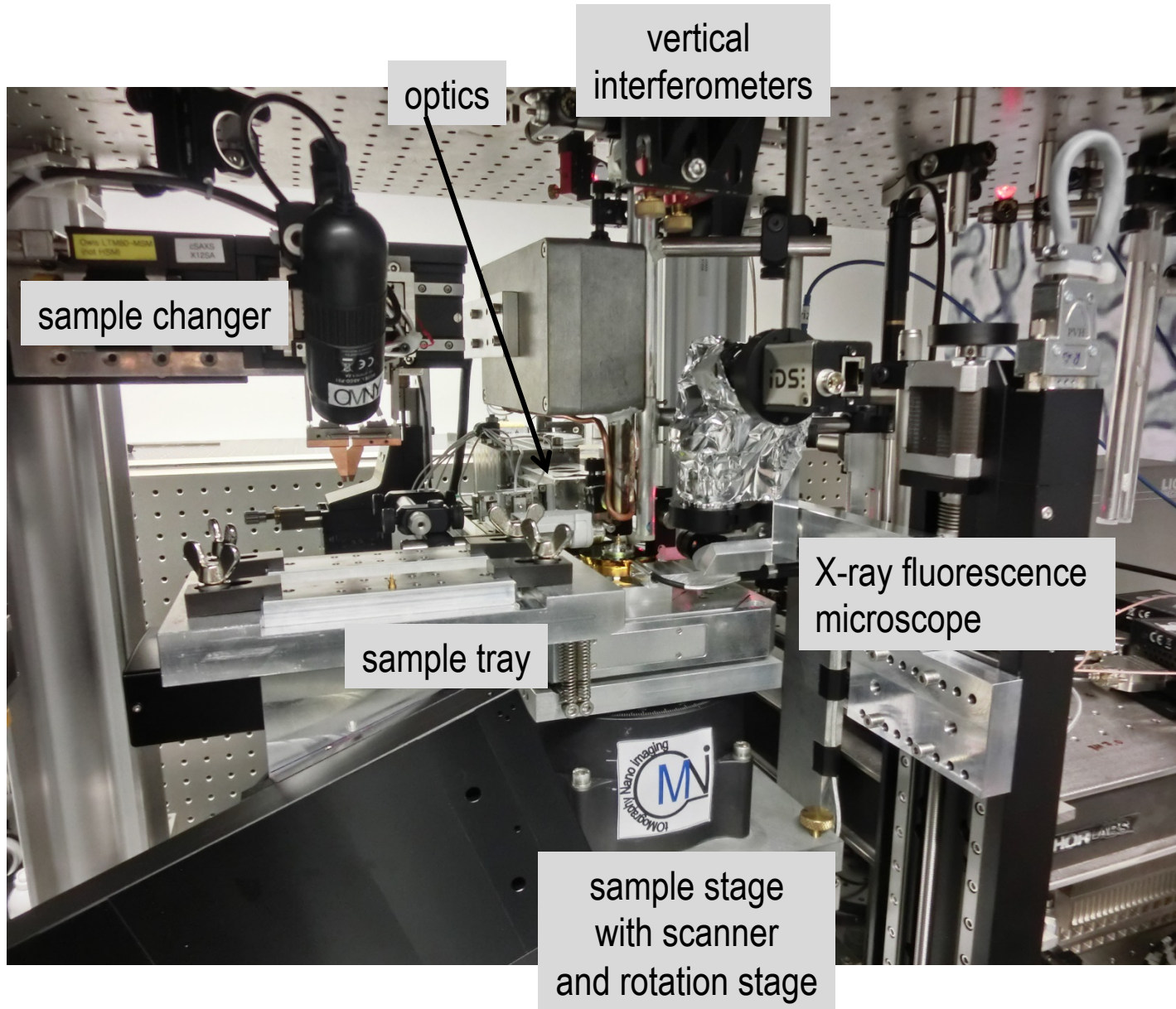
OMNY (tOMography Nano crYo)

- + optimized mechanical structures
- + cryogenic environment and UHV



M. Holler et al., Rev. Sci. Instrum. 89, 043706 (2018)

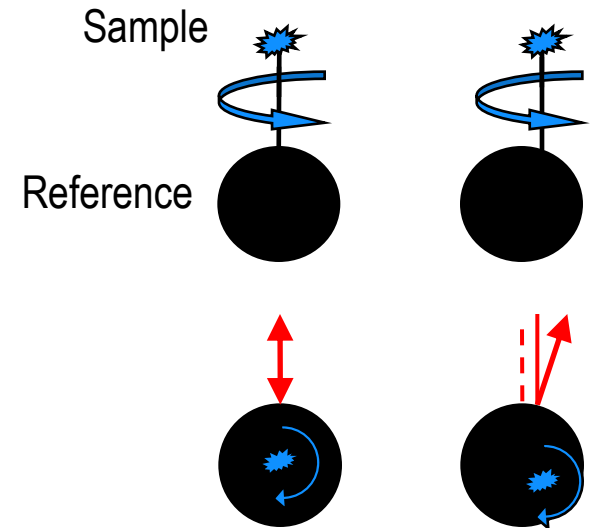
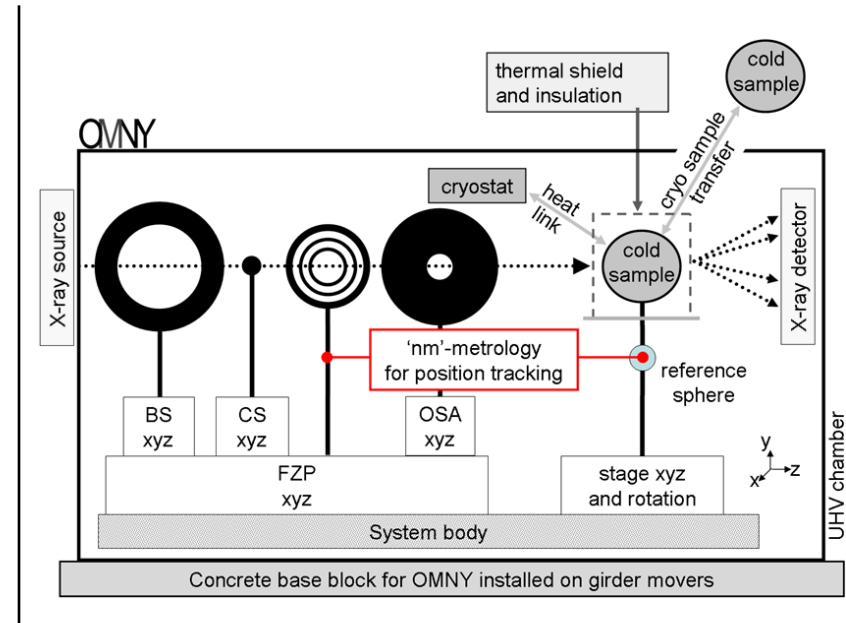
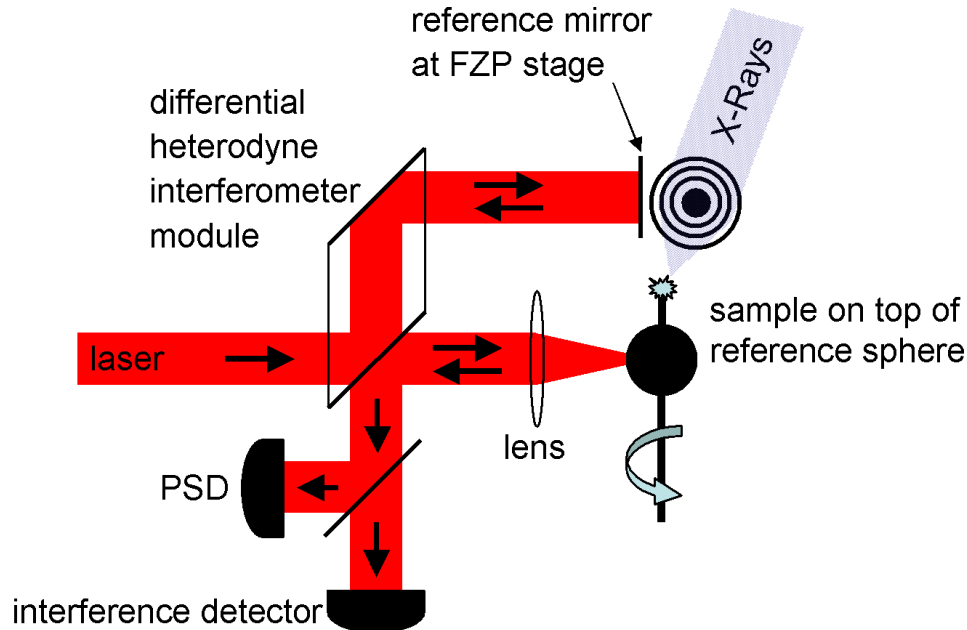
fIOMNI (flexible tOMography Nano Imaging)



Metrology for OMNY: Tracking interferometer

Position sensitive detector measures sphere motion perpendicular to laser beam propagation.

Closed loop: interferometer tracks the reference sphere and keeps pointing at its center

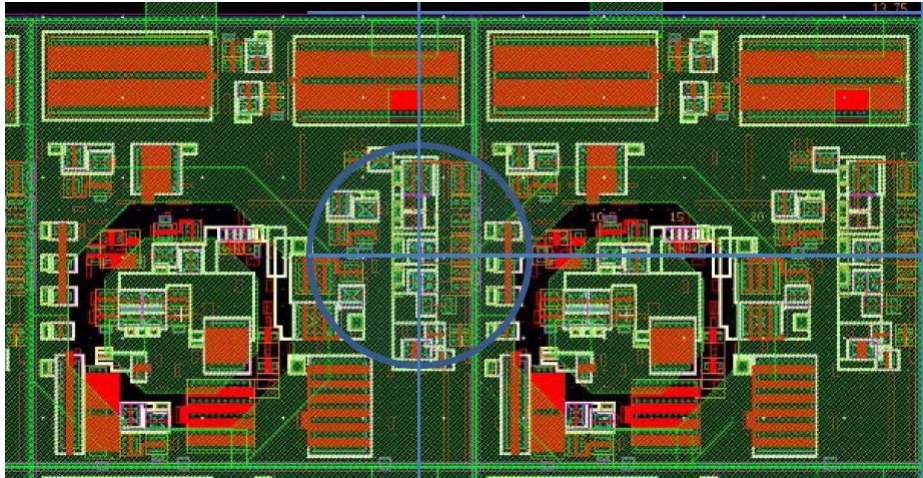


Compensation of mechanical tracking error motion needed – details in

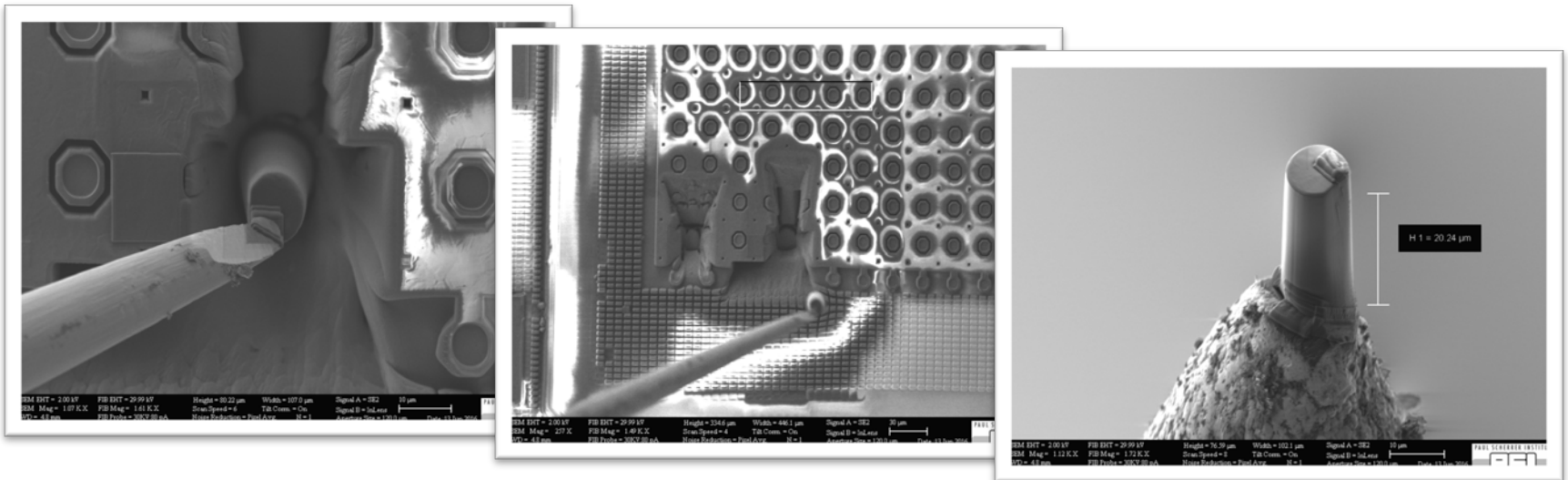
M. Holler and J. Raabe, Opt. Eng. 54(5) 054101 (2015)

Pat. publication no. WO 2012079875 A1

IC imaging – typical sample preparation

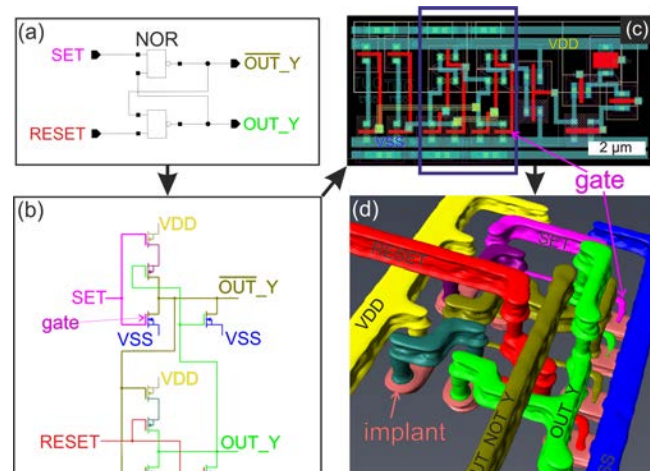
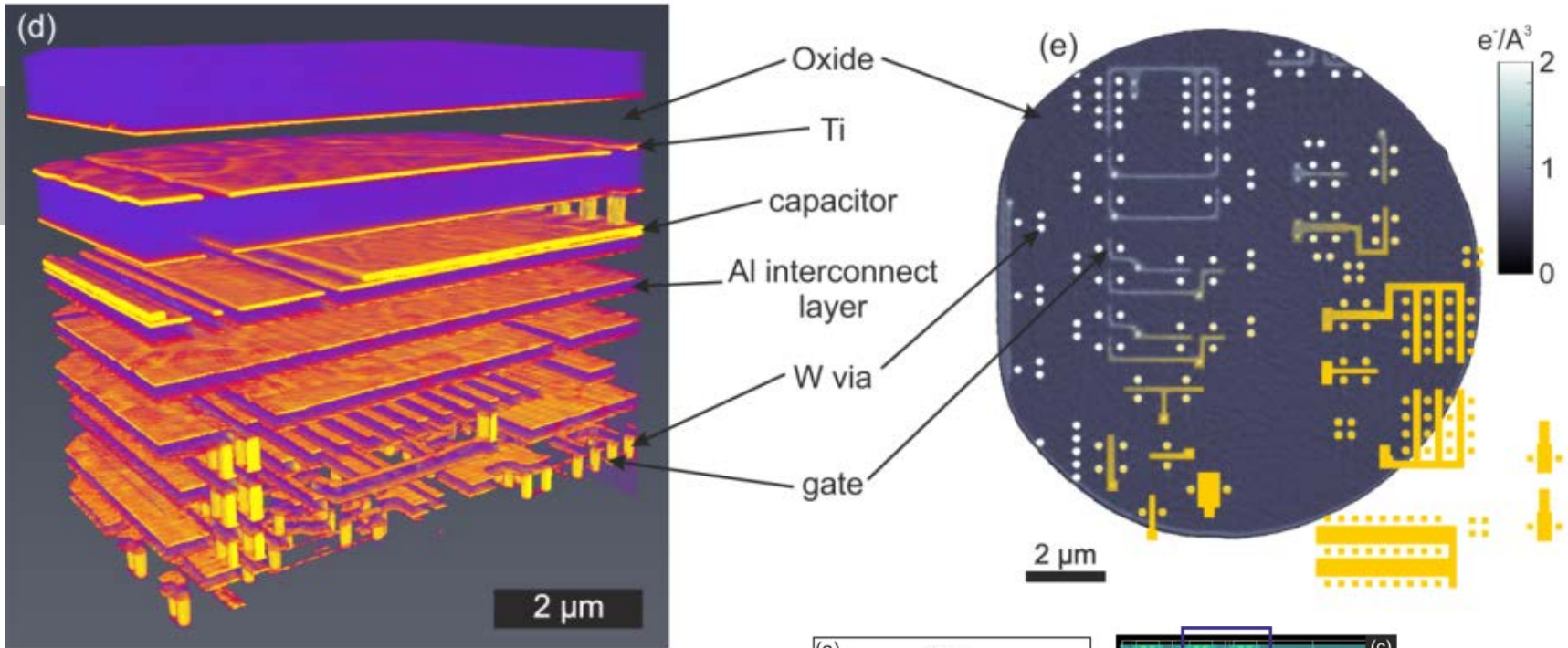


UMC 110 nm technology
hybrid silicon pixel detector
25 μm pixel pitch

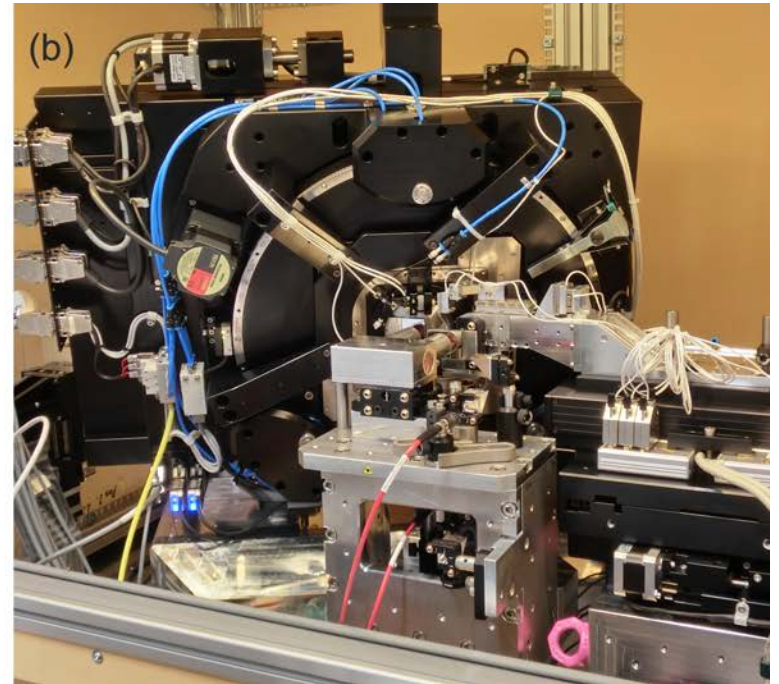
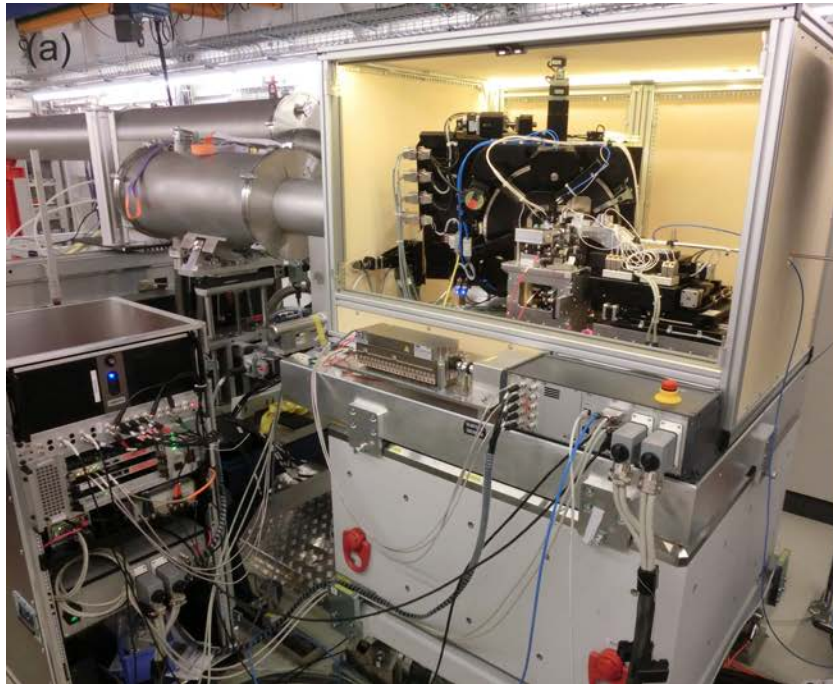


- select region in sample preparation step
- volume limited by thickness, limited by transmission

Detector ASIC - tomography result

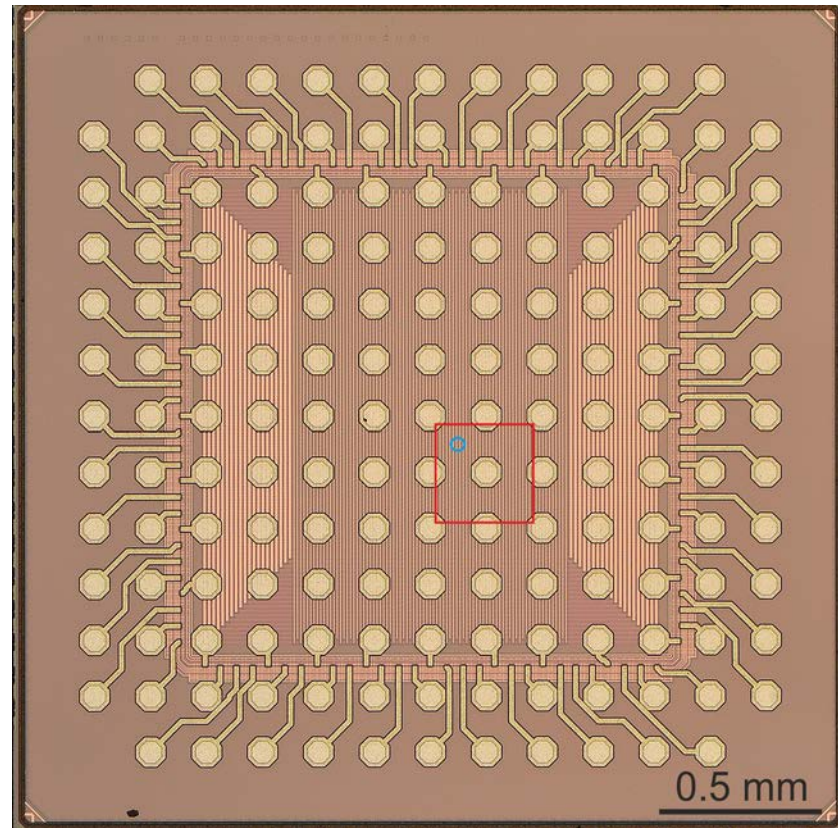


LamNI installed at the cSAXS beamline

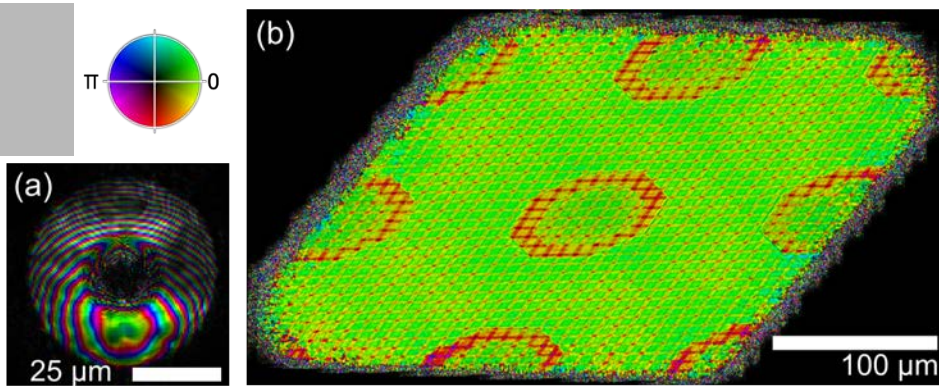


M. Holler et al., Nature Electronics 2, 464 (2019)
<https://rdcu.be/bTudW>

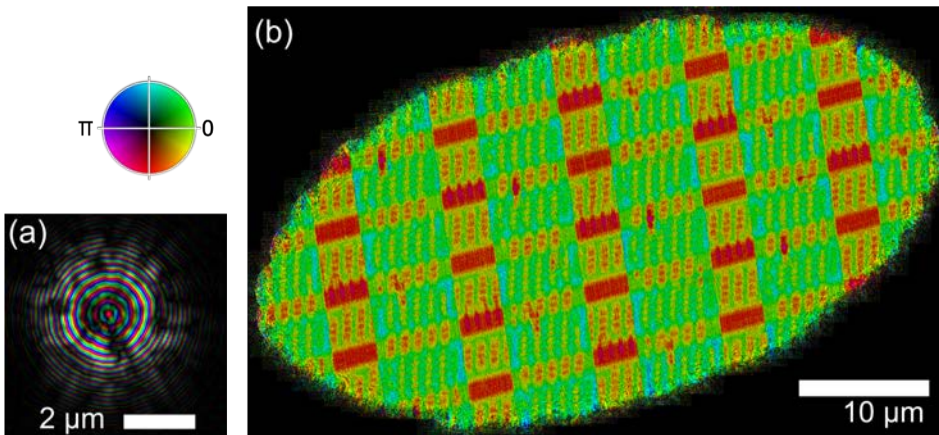
Photograph of IC measured
 16 nm FinFET technology
 mechanically polished an entire
 chip of 2.5x2.5 mm² to a substrate
 thickness of about 20 μm
 Mounted in LamNI and measured
 at 6.2 keV two laminograms with an
 Eiger detector module in air at 2.3
 m distance.



LamNI – measurement of an IC

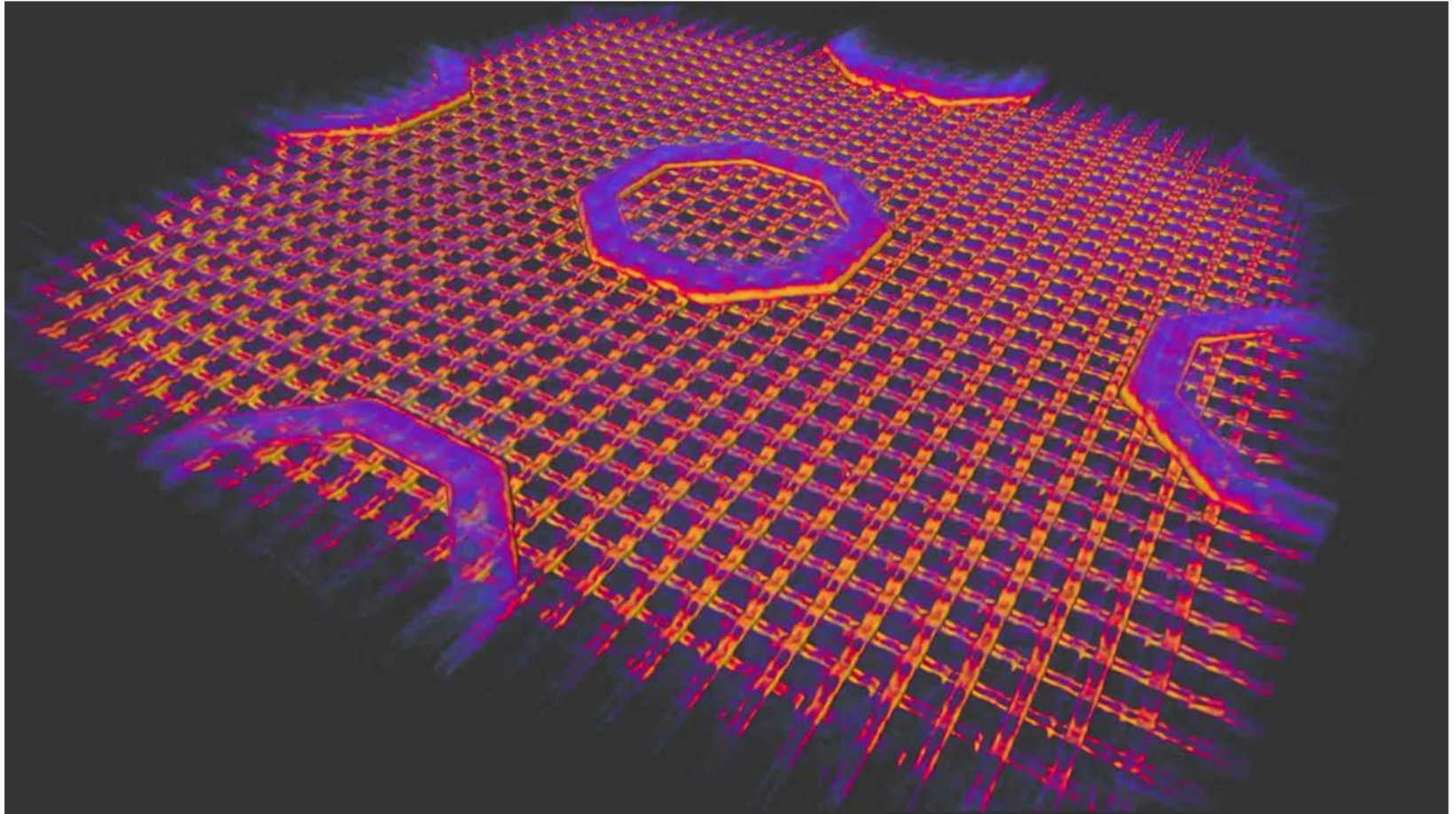


Low resolution overview scan
near-field ptychography,
300x300 μm^2 (square in sample plane)
by stitching 25 regions 70x70 μm^2
step size of 10 μm
14 sec per projection including all overhead
300 projections



High resolution ptychography scan
circular in sample plane, diameter 40 μm^2
485 scan points, 0.7 μm , 0.1 s
76 s per projection incl. all overhead
2872 projections

M. Holler et al., Nature Electronics 2, 464 (2019)
<https://rdcu.be/bTudW>



high-resolution voxel size was 13.0 nm and that volume covers 3800x3800x600 elements

M. Holler et al., Nature Electronics 2, 464 (2019)
<https://youtu.be/GvyTiK9CNO0>

Questions?

